

<b>INFORMATION DISCLOSURE CITATION</b>  <b>PTO-1449</b>		ATTY. DOCKET NO.	SERIAL NO.			
		P132-US	Not Yet Assigned			
		APPLICANT Jim Dunphy, et al.				
		FILING DATE Herewith		GROUP Not Yet Assigned		
<b>U.S. PATENT DOCUMENTS</b>						
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
Dle	U.S Pub App No. 2003/0002019	1/2/03	Miller			
	U.S Pub App No. 2002/0056898	5/16/02	Lopes, et al.			
	U.S Pub App No. 2002/0063322	5/30/02	Robbins, et al.			
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	5,694,740	12/9/97	Martin, et al.			
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Dle	5,610,438	3/11/97	Wallace, et al.			
	5,512,374	4/30/96	Wallace, et al.			
<b>FOREIGN PATENT DOCUMENTS</b>						
EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION
						YES
						<input type="checkbox"/> <input type="checkbox"/>
<b>OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)</b>						
Dle	"Lubrication of Digital Micromirror Devices" Henck, Tribology Letters 3 (1997) 239-247					
	Micromotor Operation in a Liquid Environment" Dhuler, IEEE 1992 pgs 10-13					
	"Optimization of Lubricants for silica Micromotors" Zarrd, Sensors and Actuators A 46-47 (1995) 598-600					
	"Fabrication of packaged thin beam structures by an improved driving method" Masato Ohtsu, IEEE (1996) 0-7803-2985-6, pgs 228-233					
	"Operation of electrostatic micromotors in liquid environments" Mehran Mehregany, J. Micromech. Microeng. 2 (1992) 1-3					
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	"Micromotor dynamics in lubricating fluids" Keren Deng, J. Micromech. Microeng. 4 (1994) 266-269					
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	"Friction and Pull-off Force on Silicon Surface Modified by FIB" Ando IEEE 1996, 0-7803-2985-6/96, pgs 349-353					
	"Measurement of Micromotor Dynamics in Lubricating Fluids" Deng IEEE					
Dle	"Friction and Wear studies on Lubricants and materials Applicable to MEMS" Shigehisa Suzuki, IEEE 1991, pgs 143-147					
EXAMINER	Dle	DATE CONSIDERED		7/2005		

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

<b>INFORMATION DISCLOSURE CITATION</b> <b>APR 28 2005</b> <b>PTO-1449</b> <b>SHEET 1 OF 2</b>		ATTY. DOCKET NO.	SERIAL NO.
		P132-US	10/811,449
		APPLICANT Dunphy, et al.	
		FILING DATE 3/26/04	GROUP Not Yet Assigned

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	6,204,085	3/20/01	Strumpell, et al.			
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	2004/0125346	7/1/04	Huibers			

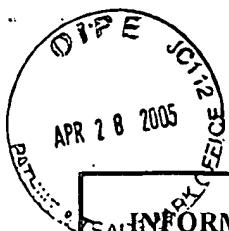
**FOREIGN PATENT DOCUMENTS**

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**OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)**

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	W. Robert Ashurst et al., VAPOR PHASE ANTI-STICKTION COATINGS FOR MEMS, Pgs 1-6.
	W. Robert Ashurst, et al., NANOMETER-THIN TITANIA FILMS WITH SAM-LEVEL STICKTION AND SUPERIOR WEAR RESISTANCE FOR RELIABLE MEMS PERFORMANCE, 4 pgs.
	B.C. Bunker, et al., THE IMPACT OF SOLUTION AGGLOMERATION ON THE DEPOSITION OF SELF-ASSEMBLED MONOLAYERS, 2000 American Chemical Society, Pgs 7742-7751.
	W. Robert Ashurst, et al., ALKENE BASED MONOLAYER FILMS AS ANTI-STICKTION COATINGS FOR POLYSILICON MEMS, Berkeley Sensor & Actuator Center, 4 pgs.
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		APPLICANT Dunphy, et al.				
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<b>U.S. PATENT DOCUMENTS</b>						
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
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	2004/0100594	5/27/04	Huibers, et al.	→		
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<i>Dle</i>	5,287,096	2/15/94	Thompson, et al.	→		
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